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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Walther, Steven R.
Serial No: 09/586,492
Filed: June 2, 2000
For: METHOD AND APPARATUS FOR CONTROLLING
ION IMPLANTATION DURING VACUUM FLUCTUATION
Examiner: Stevenson, A.
Art Unit: 2812

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231, on April 6, 2001.

Lisa A. Fletcher
Lisa A. Fletcher

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

Sir:

In response to the January 9, 2001 Office Action, please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend claims 15 and 30 as follows:

15. (Amended) The method of claim 14, wherein the step of using a scale factor comprises:
using a scale factor that has been determined based on calculated beam path length neutral particle density products that are obtained, at least in part, from a model of an ion beam path and a vacuum system.

30. (Amended) The apparatus of claim 29, wherein the controller uses a scale factor that has been determined based on calculated beam path length neutral particle density products